

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	18	(overlay with budget) and wafer and residual	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/11/25 19:27
L2	28	("4757207" "4861148" "4929083" "5124927" "5262257" "5285236" "5438413" "5444538" "5477058" "5700602" "5757507" "5805290" "5824441" "5877861" "5953128" "6023338" "6064486" "6079256" "6130750" "6137578" "6142641" "6143621" "6153886" "6163366" "6204912" "6218200" "6417929").PN. OR ("6699627"). URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/11/25 19:32



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[PDF] Special Focus

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... different baseline signatures, the prediction **error** convergence ... and spatial locations of **fields** are different ... to-wafer and within-wafer sampling optimization ...

www.kla-tencor.com/company/magazine/summer03/More%20and%20Less%20Article.pdf - Supplemental Result - [Similar pages](#)

[PDF] An Automated Method for Overlay Sample Plan Optimization

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... the difference in yield loss between full- **wafer** and sub ... Fewer **field** plans, for example, four-**field** plans, result ... sampling plan with a pre- diction **error** of no ...

www.kla-tencor.com/company/magazine/fall01/coverstory_automated_method.pdf - Supplemental Result - [Similar pages](#)

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residual error. The four scenarios examined are **wafer** scale ... Here, the **residual error** is a y. **mean** offset across the wide **field** stepper domain. ...

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sizes (large **field** steppers) to increase **wafer** throughput on less critical ...

The **residual error** is manifested as a y **mean** offset across the large **field** ...

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TOTAL tool + **wafer**-heating differential stitching **error** = 2nm **mean** + ...

Large-scale **residual wafer**-heating **error** (or other instabilities) = 5 nm 3-sigma. ...

www.bell-labs.com/project/SCALPEL/papers99/spie99ol.pdf - [Similar pages](#)

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was achieved with films having **mean residual** layers of 25nm with a 3σ variation of 15nm. ... distortion map of 27 **fields** after first order **error** corrections ...

www.molecularimprints.com/NewsEvents/tech_articles/MNE%202004-SL-81.pdf - [Similar pages](#)

[PDF] Design and Performance of a Step and Repeat Imprinting Machine

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2) Full **wafer residual** thickness control to enable practical etching ... **mean** for the **fields** are all within 2 nm, 3σ. The majority of this **error** is **residual** ...

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the **residual** component, or the random **error** remaining after subtracting feature response to all non- ... average **field** CD differences from **wafer mean**). ...

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[PDF] Semiconductor **wafer** defect detection using digital holography

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Defect inspection **metrology** is an integral part of the yield ramp and ...

fields of view from adjacent die on the **wafer**. To isolate which **field** of view a ...